

**IN THE UNITED STATES PATENT AND TRADEMARK OFFICE**

Applicant(s): SHIBATA, et al.  
Serial No.: 10/699,934  
Filed: November 4, 2003  
For: METHOD AND APPARATUS FOR INSPECTING DEFECTS  
Group: 2877  
Examiner: T. Ton  
Conf. No.: 3889

**AMENDMENT**

Commissioner for Patents  
P.O. Box 1450  
Alexandria, Virginia 22313-1450

April 9, 2007

Sir:

In response to the Office Action dated November 7, 2006, please amend the above-identified application as listed below and as set forth on the following pages:

**Amendments to the Claims**

**Remarks** are included following the amendments